

Pellicle Intermediary Body, Pellicle, Method for Manufacturing of Pellicle Intermediary Body, and Pellicle  
Manufacturing Method

ABSTRACT OF THE DISCLOSURE

5

A pellicle intermediary body has a Si substrate, a Si oxide film formed on a surface of the Si substrate, and a Si layer formed on a surface of the Si oxide film. The Si layer includes a low COP (Crystal Originated Particle) portion which is a part where the number of COPs decreases as it approaches the surface of the Si layer and is formed in the part that constitutes the surface of the Si layer. A pellicle intermediary body, a pellicle, a method for  
10 manufacturing a pellicle intermediary body, and a pellicle manufacturing method that can improve the quality of the pellicle film are provided.

Fig. 13